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PATENT

FORM PTO-1449  <b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</b> (use several sheets if necessary)	SERIAL NO. 08/853,323 FILING DATE May 8, 1997	CASE NO. 7103/30 GROUP ART UNIT 3203
APPLICANT(S): Homayoun Talieh et al.		

REFERENCE DESIGNATION			U.S. PATENT DOCUMENTS			
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
GN	A1	619,399	02/1899	Fischer		
	A2	3,447,306	06/1969	Jakimcius		
	A3	3,654,739	04/1972	Stoy et al.		
	A4	3,753,269	08/1973	Budman		
	A5	3,906,678	09/1975	Roth		
	A6	4,016,857	04/1977	Hall		
	A7	4,347,689	09/1982	Hammond		
	A8	4,416,090	11/1983	Jonasson		
	A9	4,593,495	06/1986	Kawakami et al.		
	A10	4,628,640	12/1986	Johannsen		
	A11	4,642,943	02/1987	Taylor, Jr.		
	A12	4,704,823	11/1987	Steinback		
	A13	4,811,522	03/1989	Gill, Jr.		
	A14	4,934,102	06/1990	Leach et al.		
	A15	4,941,293	07/1990	Ekhoff		
	A16	5,081,795	01/1992	Tanaka et al.		
	A17	5,205,082	04/1993	Shendon et al.		
	A18	5,212,910	05/1993	Breivogel		
	A19	5,230,184	07/1993	Bukhman		
	A20	5,232,875	08/1993	Tuttle et al.		
	A21	5,246,525	09/1993	Sato		
	A22	5,274,964	01/1994	Simpson et al.		
	A23	5,276,999	01/1994	Bando		
	A24	5,287,663	02/1994	Pierce et al.		
	A25	5,297,361	03/1994	Baldy et al.		
	A26	5,329,732	07/1994	Karlsrud et al.		
	A27	5,329,734	07/1994	Yu		
	A28	5,335,453	08/1994	Baldy et al.		
	A29	5,399,125	03/1995	Dozier		
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EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES NO
GN	A31	EP 517 594	12/92	EPO		
GN	A32	EP 517 595	12/92	EPO		
EXAMINER G. NGUYEN			DATE CONSIDERED 2/9/98			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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GROUP ART UNIT

3203

APPLICANT(S): Homayoun Talieh et al.

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES	NO
GN	A33	2269552	11/1990	Japan			
GN	A34	2269553	11/1990	Japan			
GN	A35	62162466	11/87	Japan			
GN	A36	63267155	11/88	Japan			
GN	A37	7111256	04/1995	Japan			
GN	A38	JP 59-232768	12/1984	Japan			
GN	A39	JP 63200965	08/1988	Japan			
GN	A40	JP 63251166	10/1988	Japan			
GN	A41	JP 4-250967	09/1992	Japan			
GN	A42	DE 3411 120 A1	03/1983	Germany			
GN	A43	PCT WO 94/17957	08/1994	PCT			
GN	A44	2007784	02/1994	Russia			

EXAMINER INITIAL	OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
GN	A45	"A New Pad and Equipment Development for ILD Planarization" by Toshiyasu Beppu, Motoyuki Obara and Yausuo Minamikawa, Semiconductor World, January, 1994, MY 3/17/94
GN	A46	"Application of Chemical Mechanical Polishing to the Fabrication of VLSI Circuit Interconnections", William J. Patrick, William L. Guthrie, Charles L. Stadley and Paul M. Schiabe, J. Electrochem. Soc., Vol. 138, No. 6, June 1991, pp. 1778-1784
GN	A47	"Theory & Practice of Lubrication for Engineers", Dudley Fuller, Wiley-Interscience, 1st ed., pp. 22-25 and 86
GN	A48	Practical Ideas, June 1994, page 67

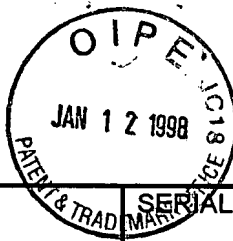
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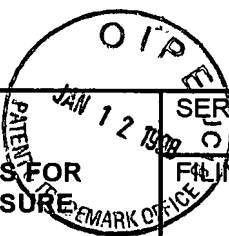
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